

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Yeong-Kwan KIM, et al.

Serial No. 09/902,607

Filed: July 12, 2001

For: Semiconductor Device Having  
Thin Film Formed by Atomic  
Layer Deposition and Method  
for Fabricating the Same

Examiner: Toniae M. Thomas

Art Unit: 2822

Atty. Docket No.: 249/258

A9  
Response  
(suppl)

SUPPLEMENTAL AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents  
United States Patent and Trademark Office  
Washington, D.C. 20231

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OFFICE OF PETITIONS

Sir:

Pursuant to the Amendment filed on February 7, 2003, attached hereto is the Certified  
English Translation of the Korean Priority Document.

Respectfully submitted,

Date: February 11, 2003

  
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PETITION and  
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This document and any concurrently filed papers are believed to be timely. Should any extension of the term be required, applicant hereby petitions the Director for such extension and requests that any applicable petition fee be charged to Deposit Account No. 50-1645.

If fee payment is enclosed, this amount is believed to be correct. However, the Director is hereby authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-1645.

Any additional fee(s) necessary to effect the proper and timely filing of the accompanying-papers may also be charged to Deposit Account No. 50-1645.